

## Electronic Patent Application Fee Transmittal

<b>Application Number:</b>	10781920			
<b>Filing Date:</b>	20-Feb-2004			
<b>Title of Invention:</b>	Method for fabricating a resist mask for patterning semiconductor substrates			
<b>First Named Inventor/Applicant Name:</b>	Odo Wunnicke			
<b>Filer:</b>	Ira Stuart Matsil/Natalie Swider			
<b>Attorney Docket Number:</b>	INF 2004 SP 00138 US			
Filed as Large Entity				
<b>Utility      Filing Fees</b>				
<b>Description</b>	<b>Fee Code</b>	<b>Quantity</b>	<b>Amount</b>	<b>Sub-Total in USD(\$)</b>
<b>Basic Filing:</b>				
<b>Pages:</b>				
<b>Claims:</b>				
<b>Miscellaneous-Filing:</b>				
<b>Petition:</b>				
<b>Patent-Appeals-and-Interference:</b>				
Notice of appeal	1401	1	510	510
Post-Allowance-and-Post-Issuance:				
<b>Extension-of-Time:</b>				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Extension - 1 month with \$0 paid	1251	1	120	120
<b>Miscellaneous:</b>				
<b>Total in USD (\$)</b>				<b>630</b>